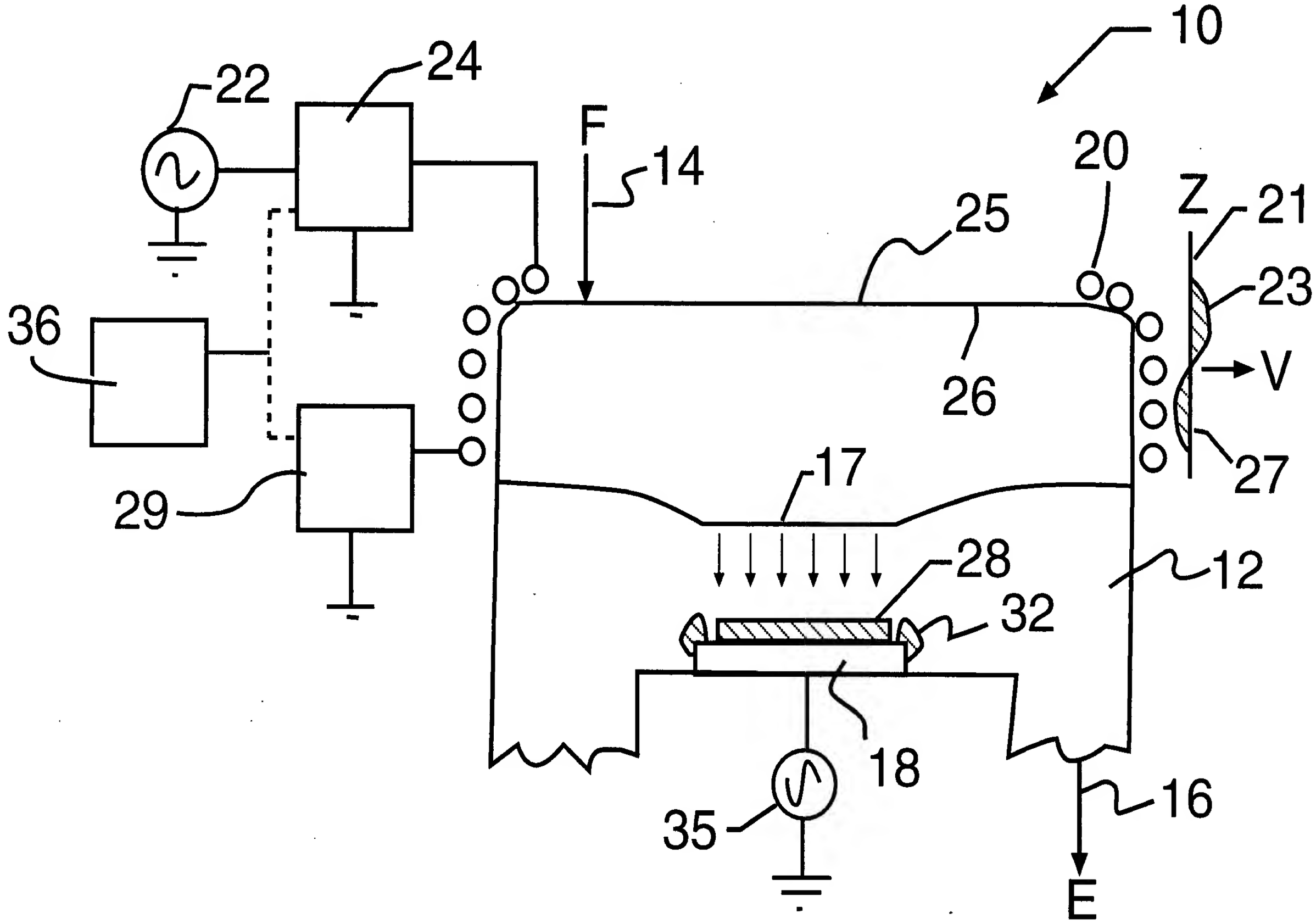


FIG. 1

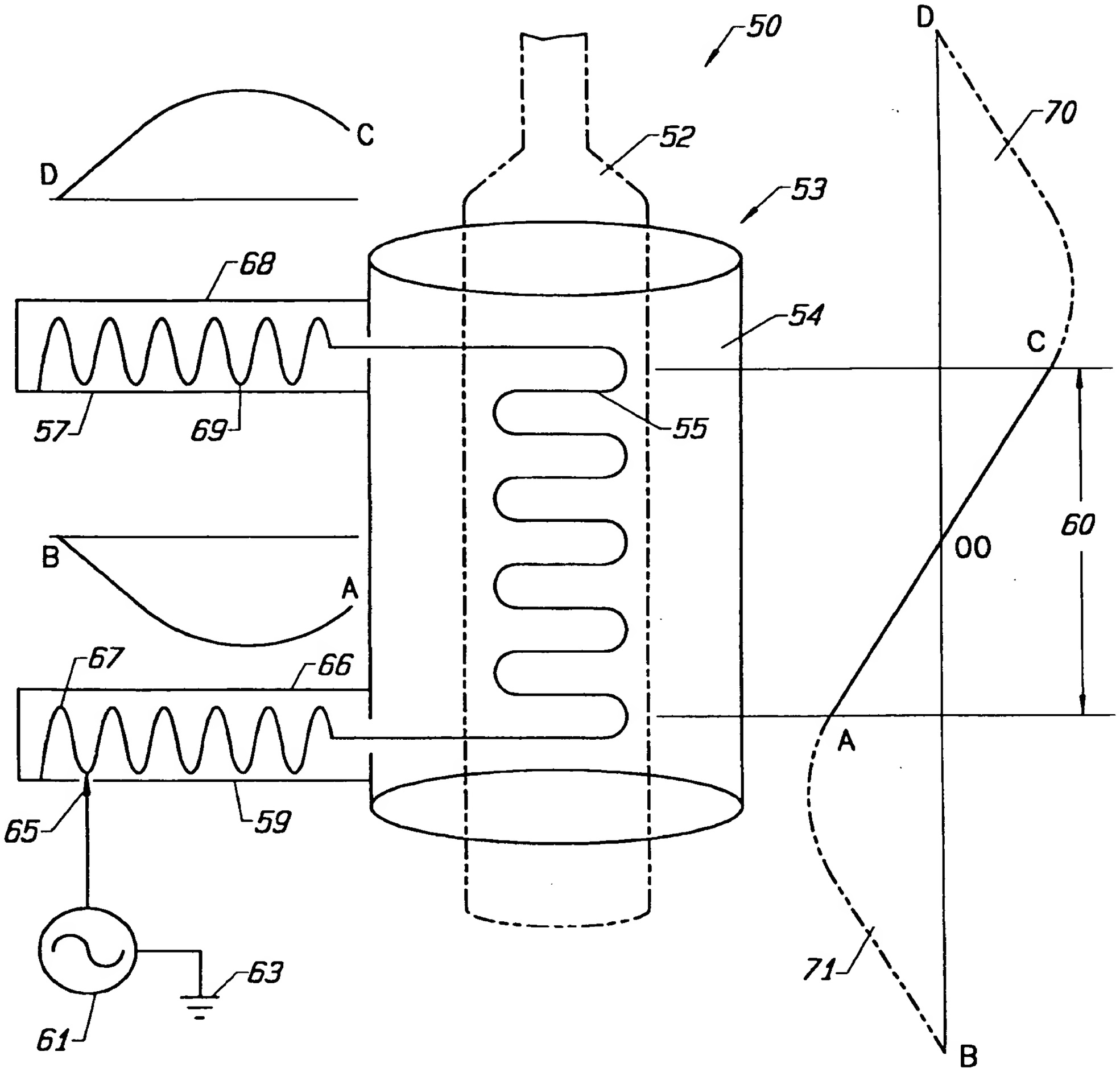


FIG. 2A

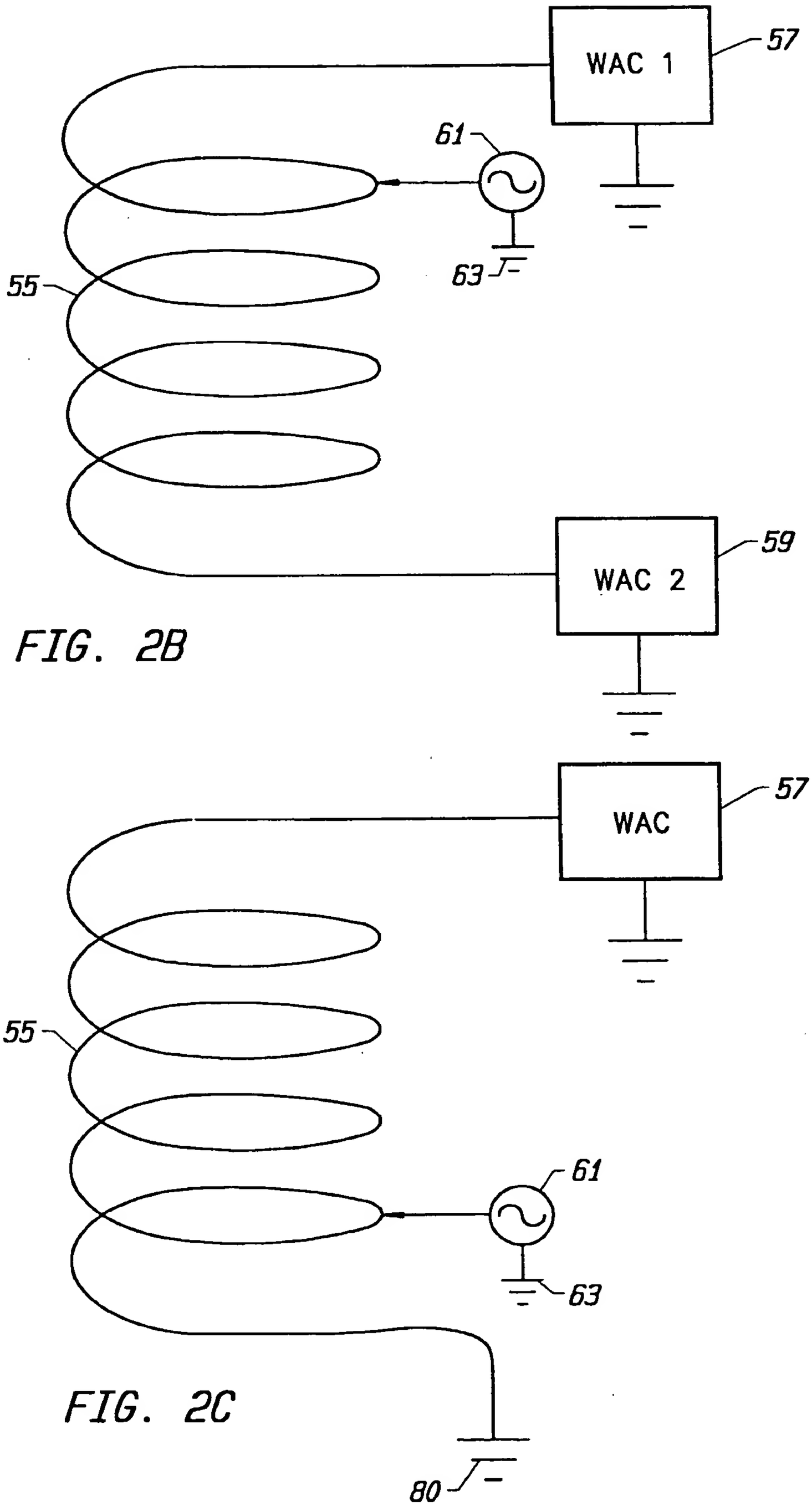


FIG. 2B

FIG. 2C

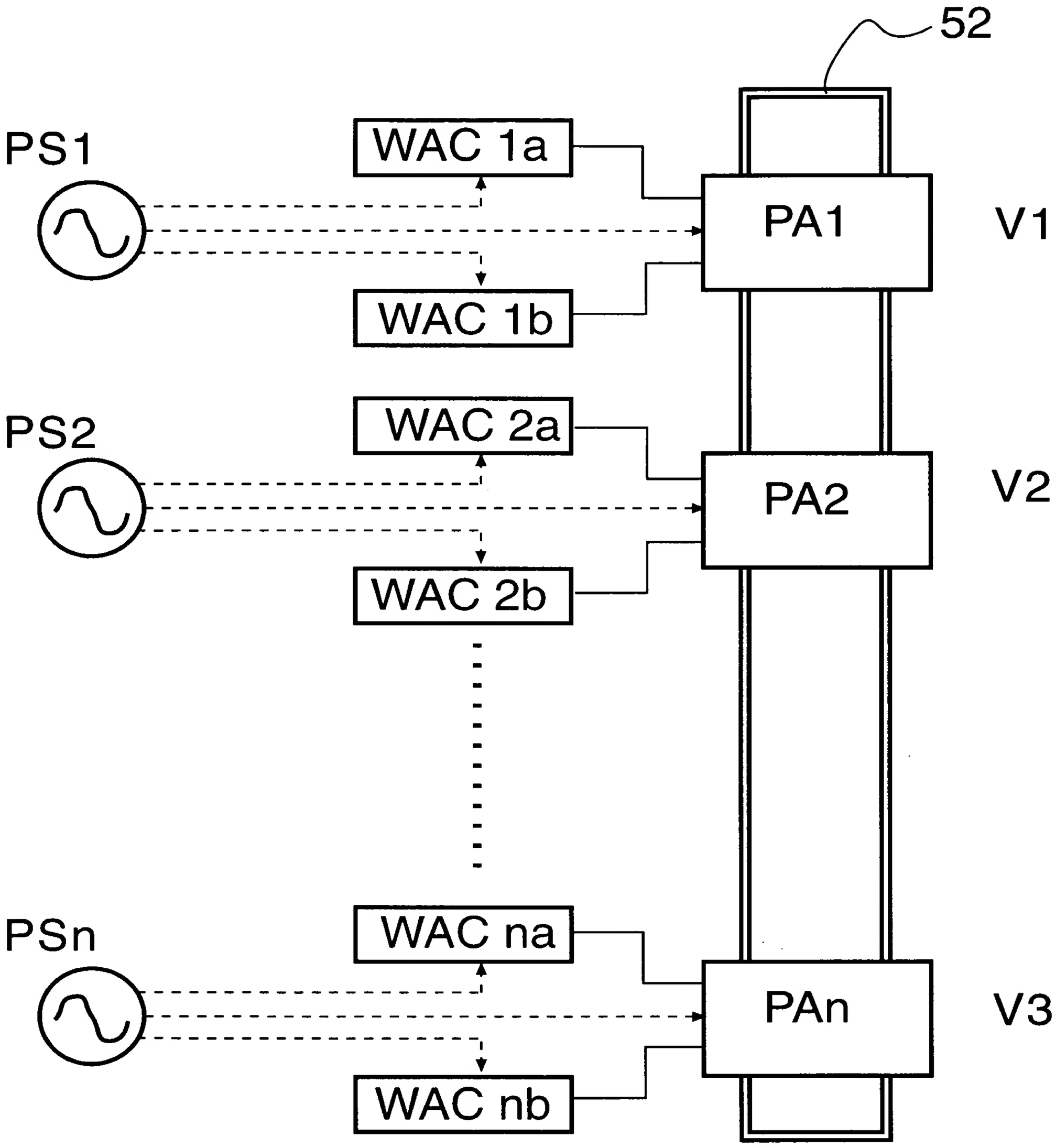


Fig. 2D

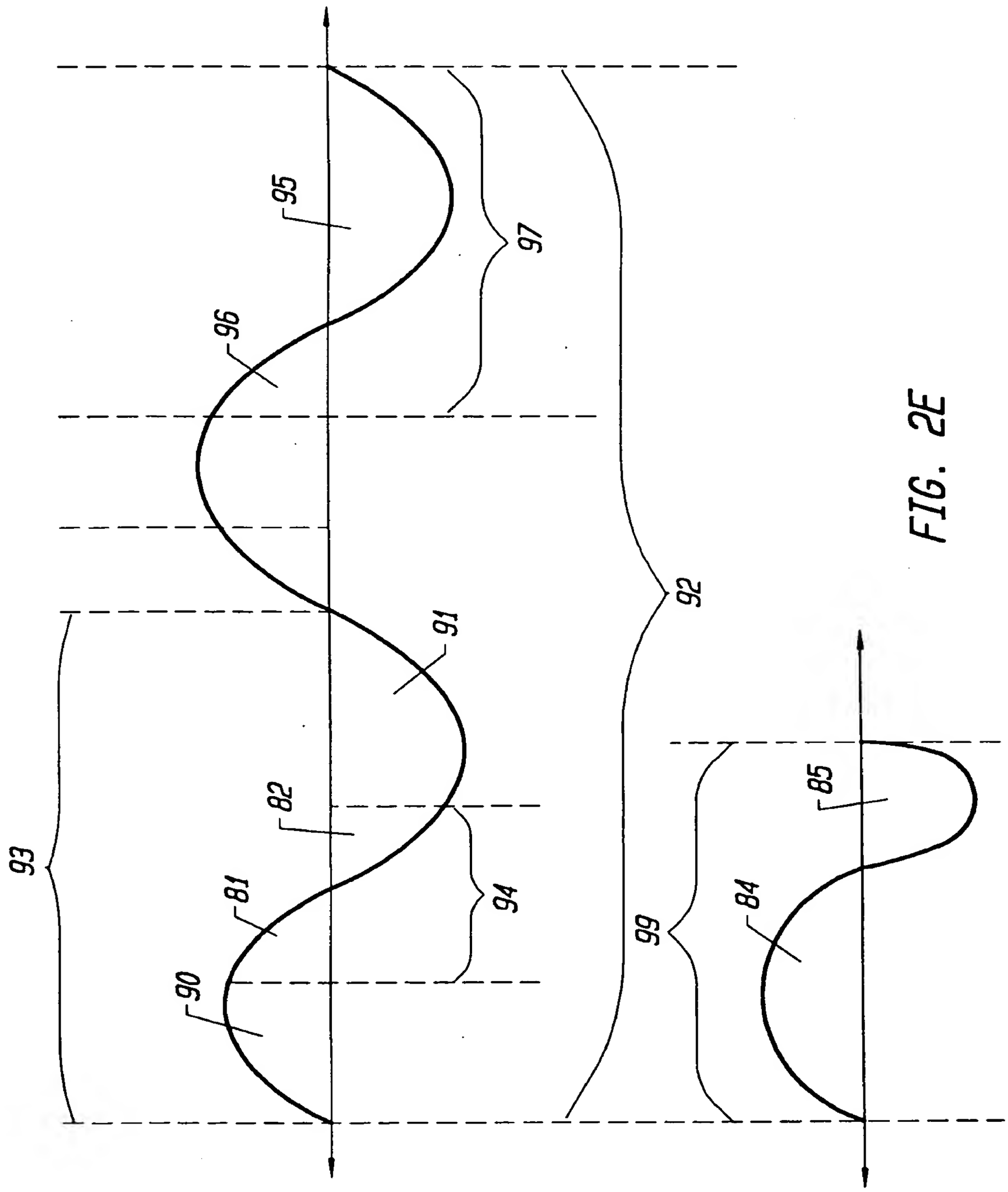


FIG. 2E

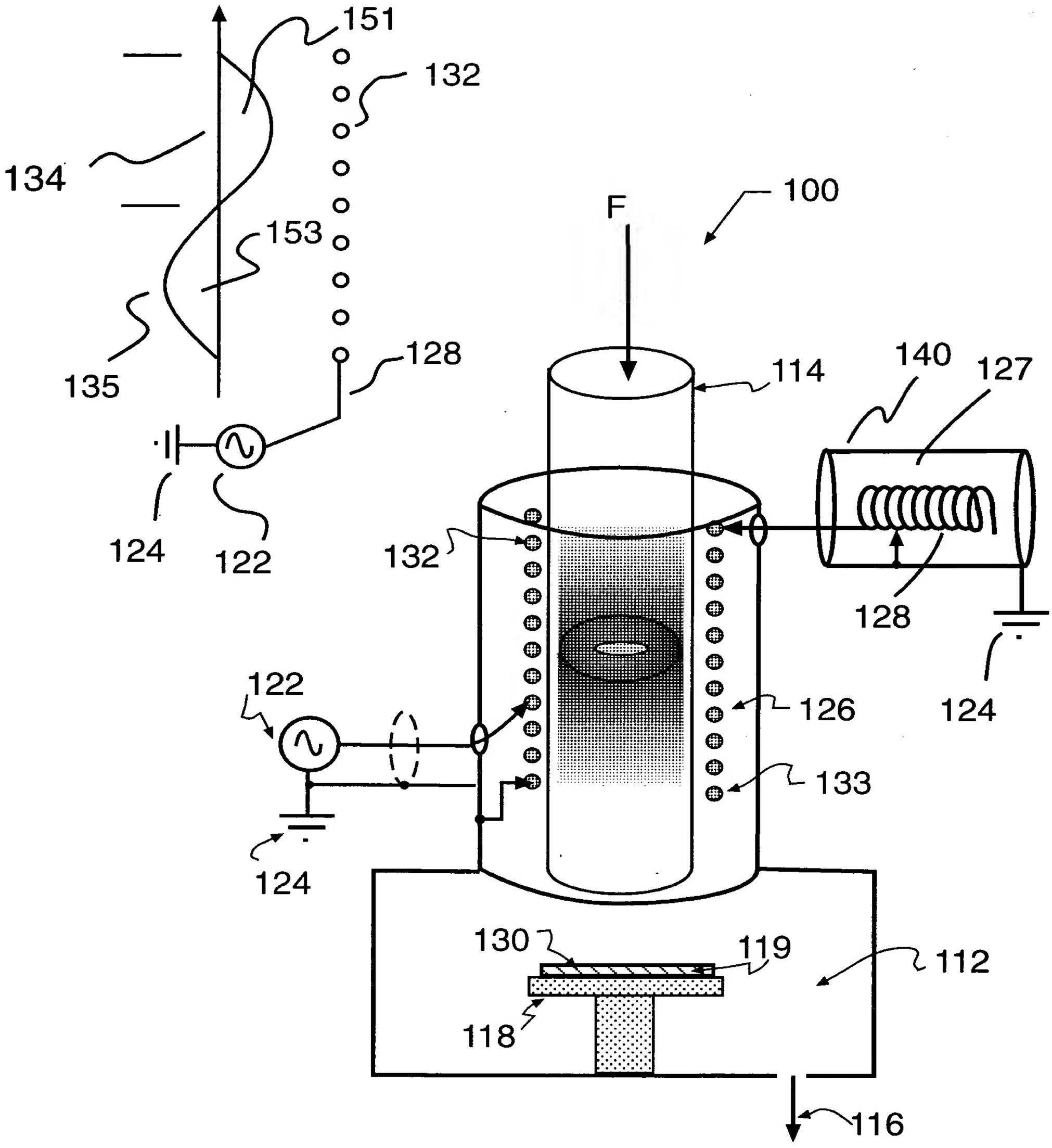


Fig. 3

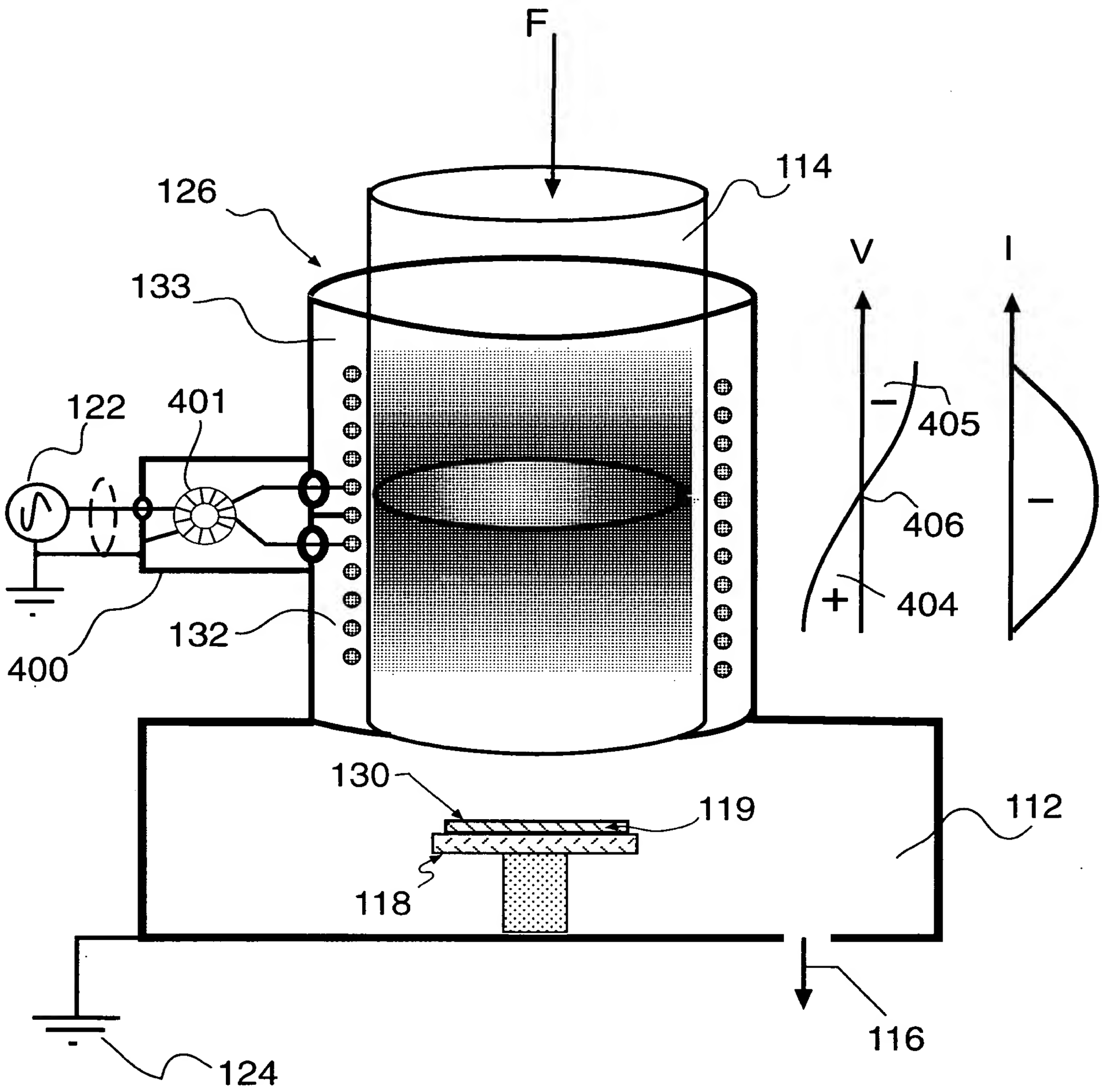


Fig. 4

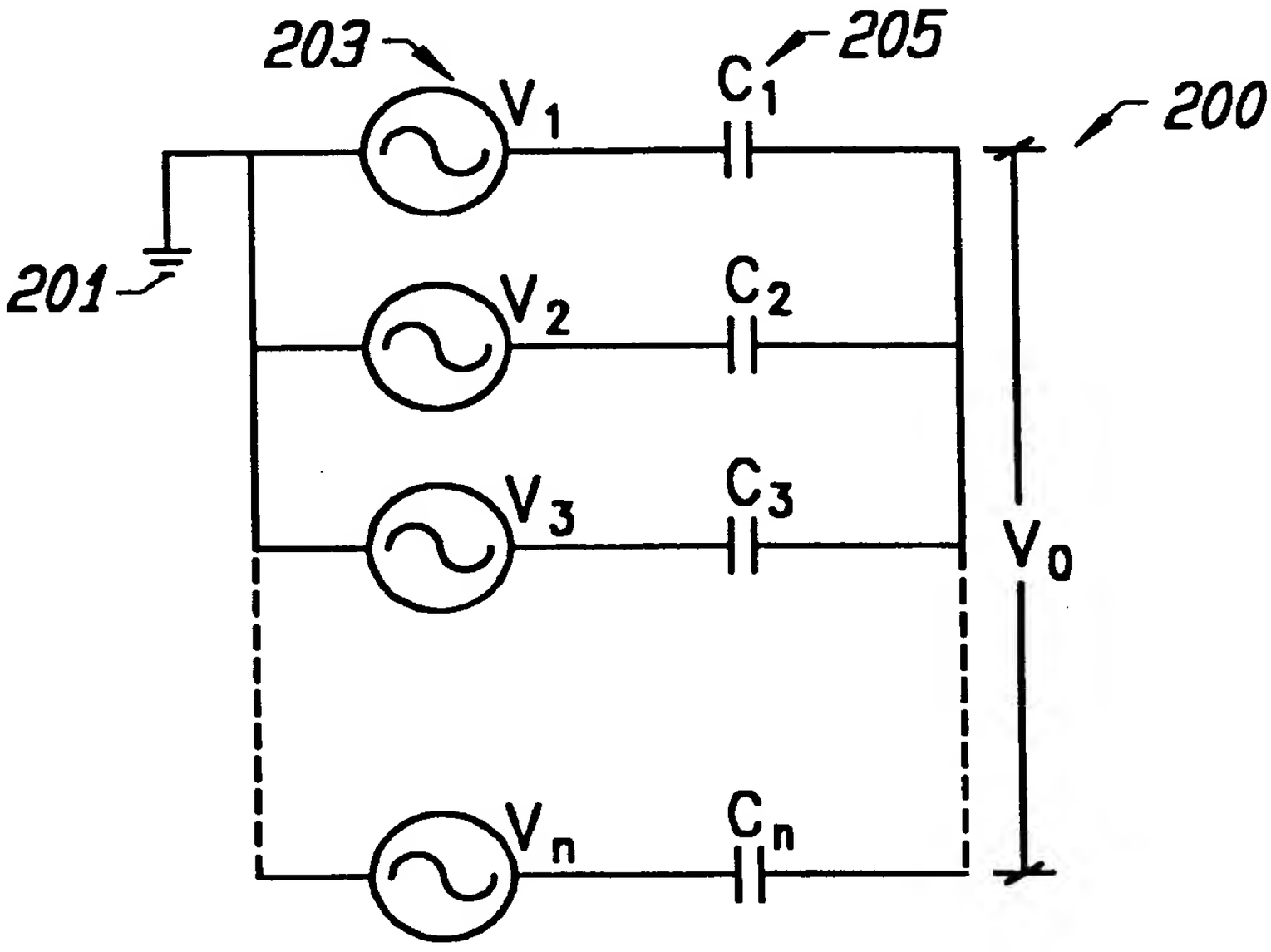


FIG. 5A

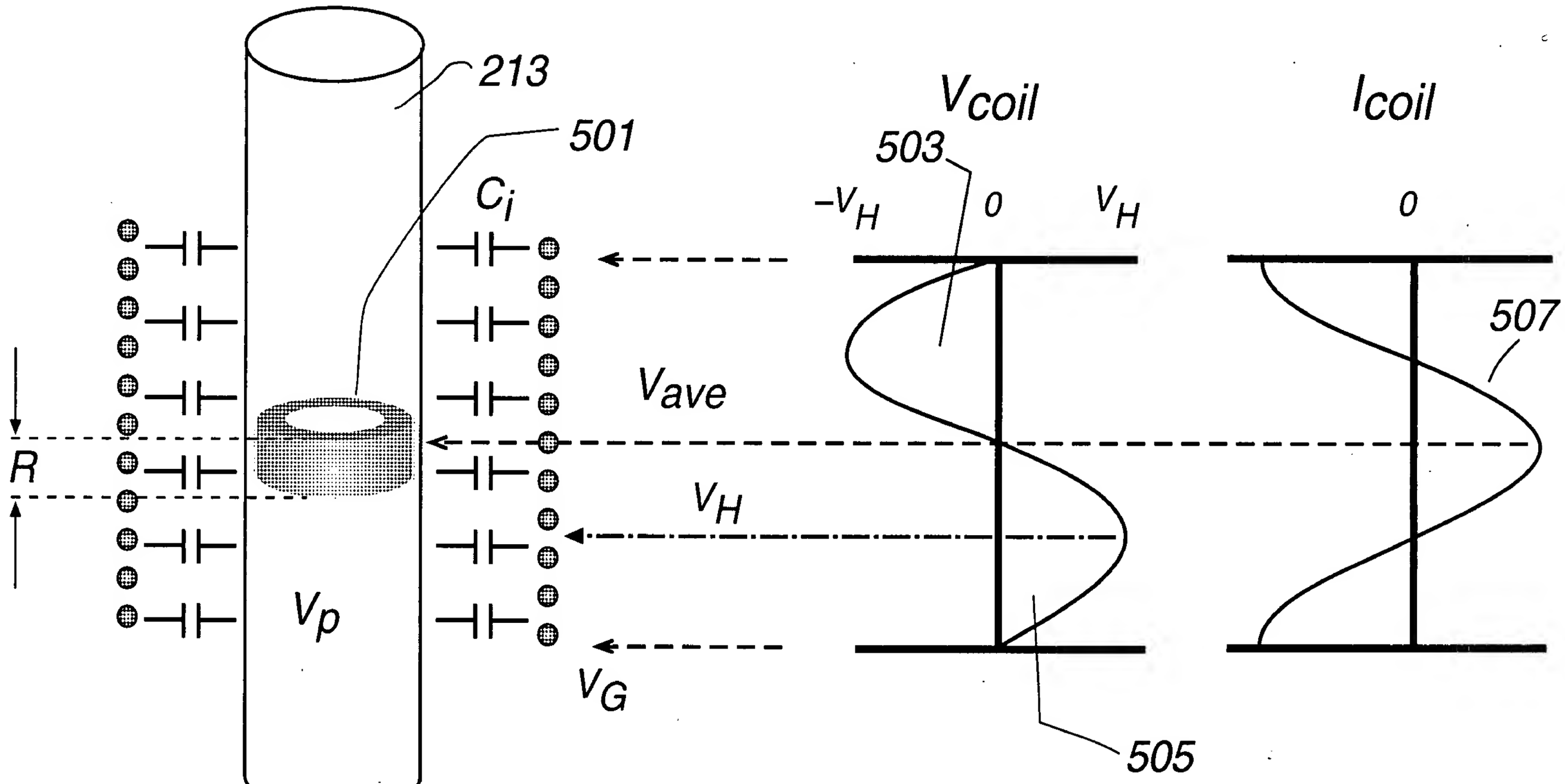


Fig. 5B

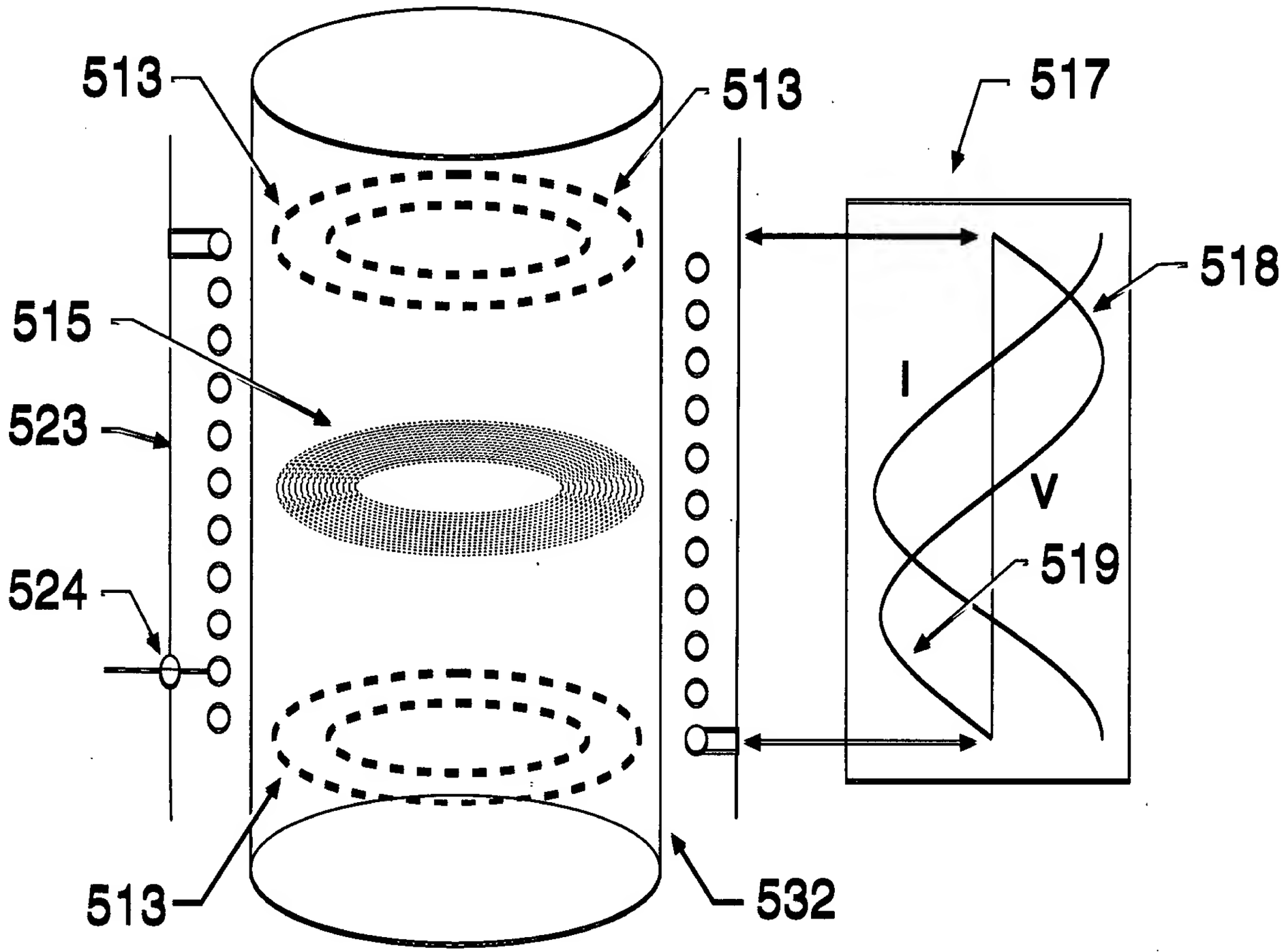


Fig. 5C

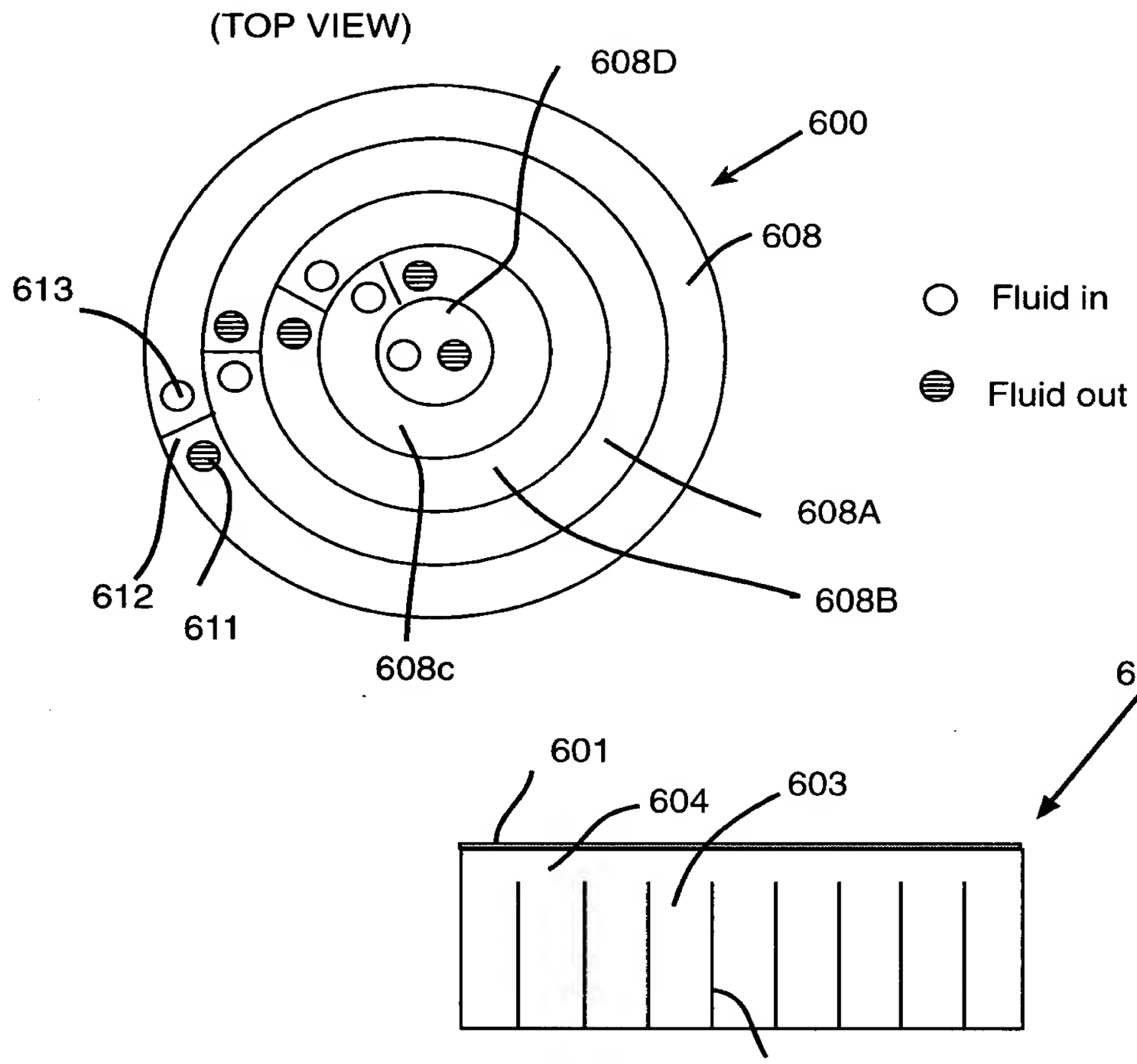


FIG. 6

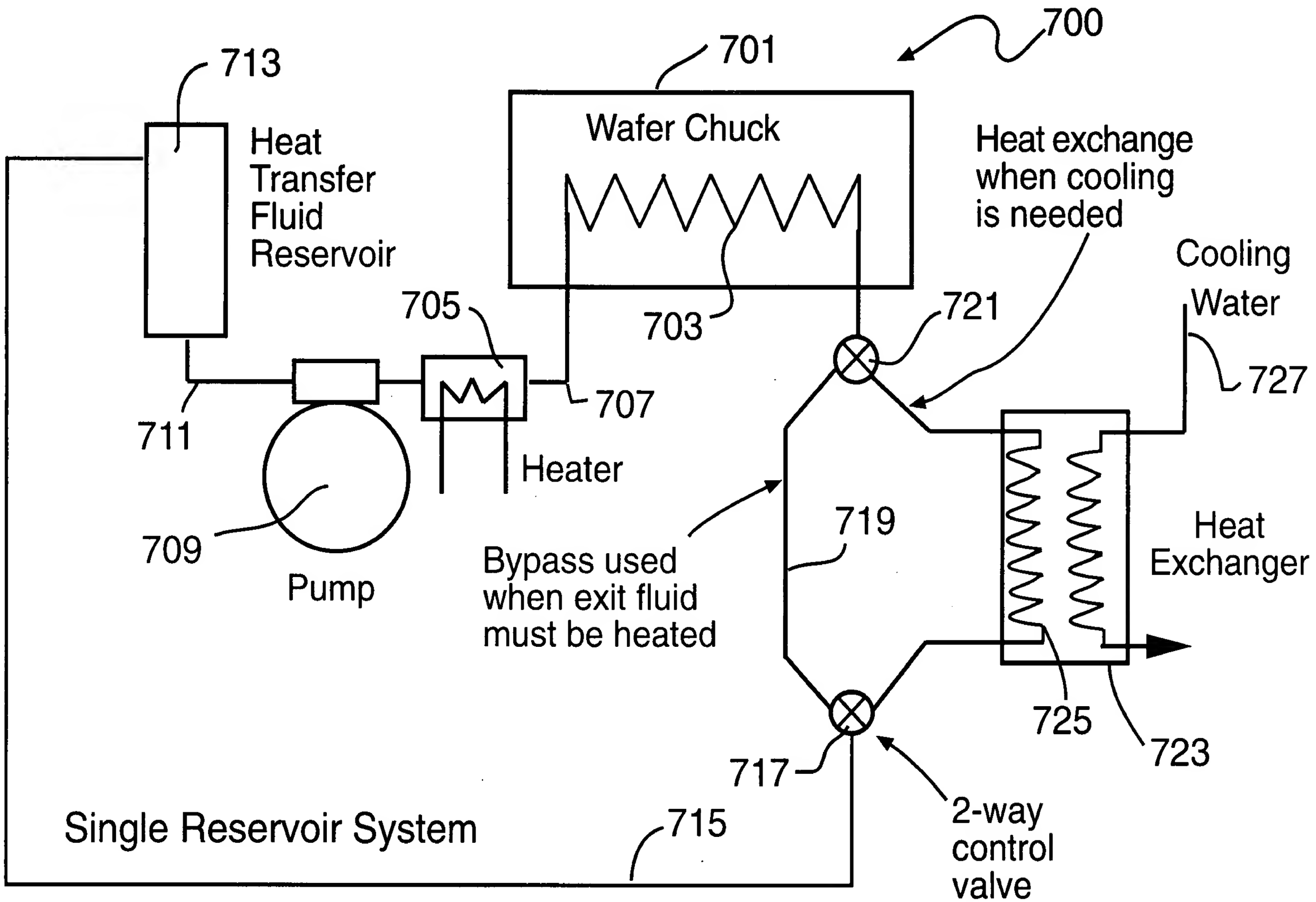


Fig. 7

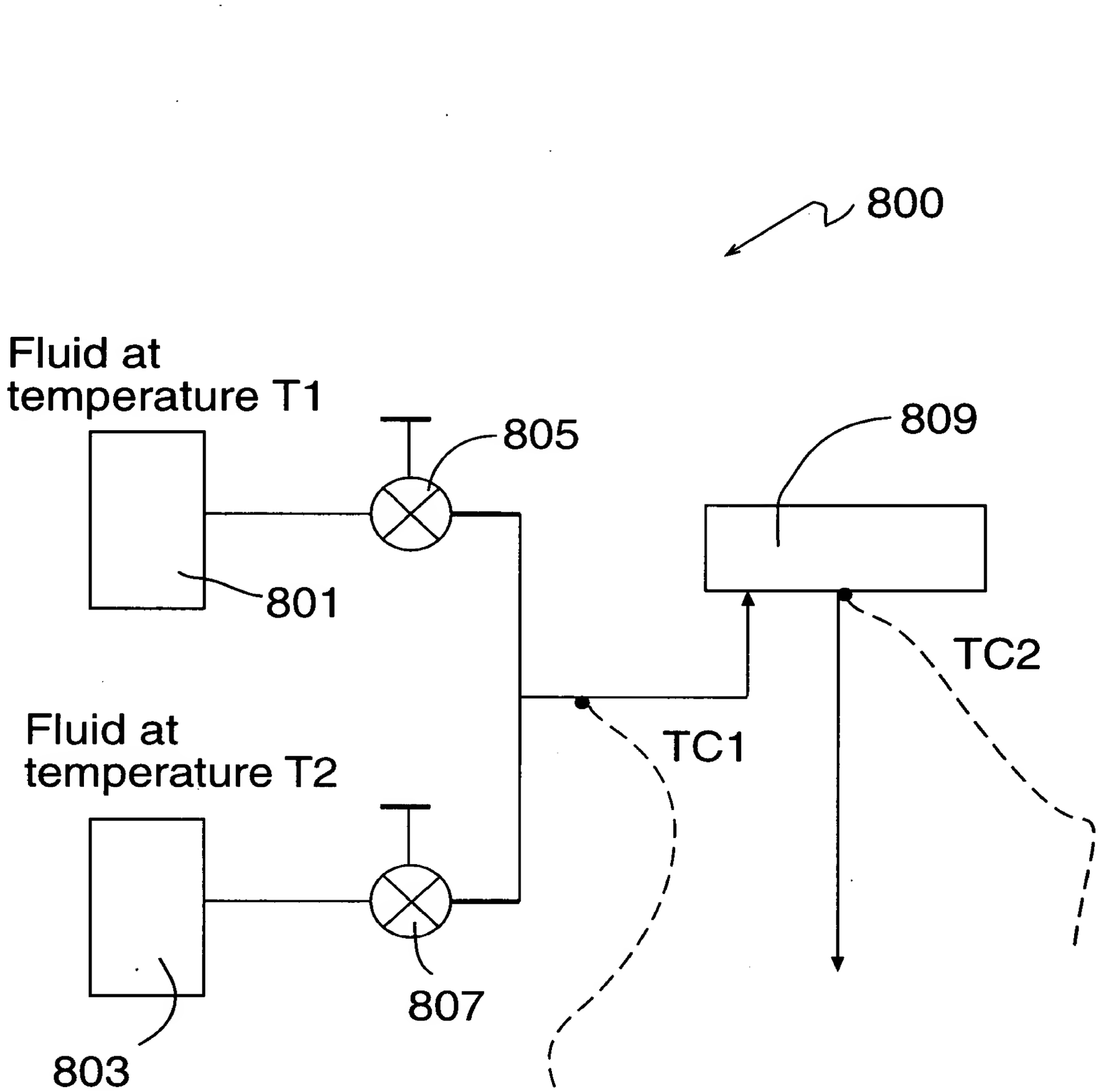


Fig. 8

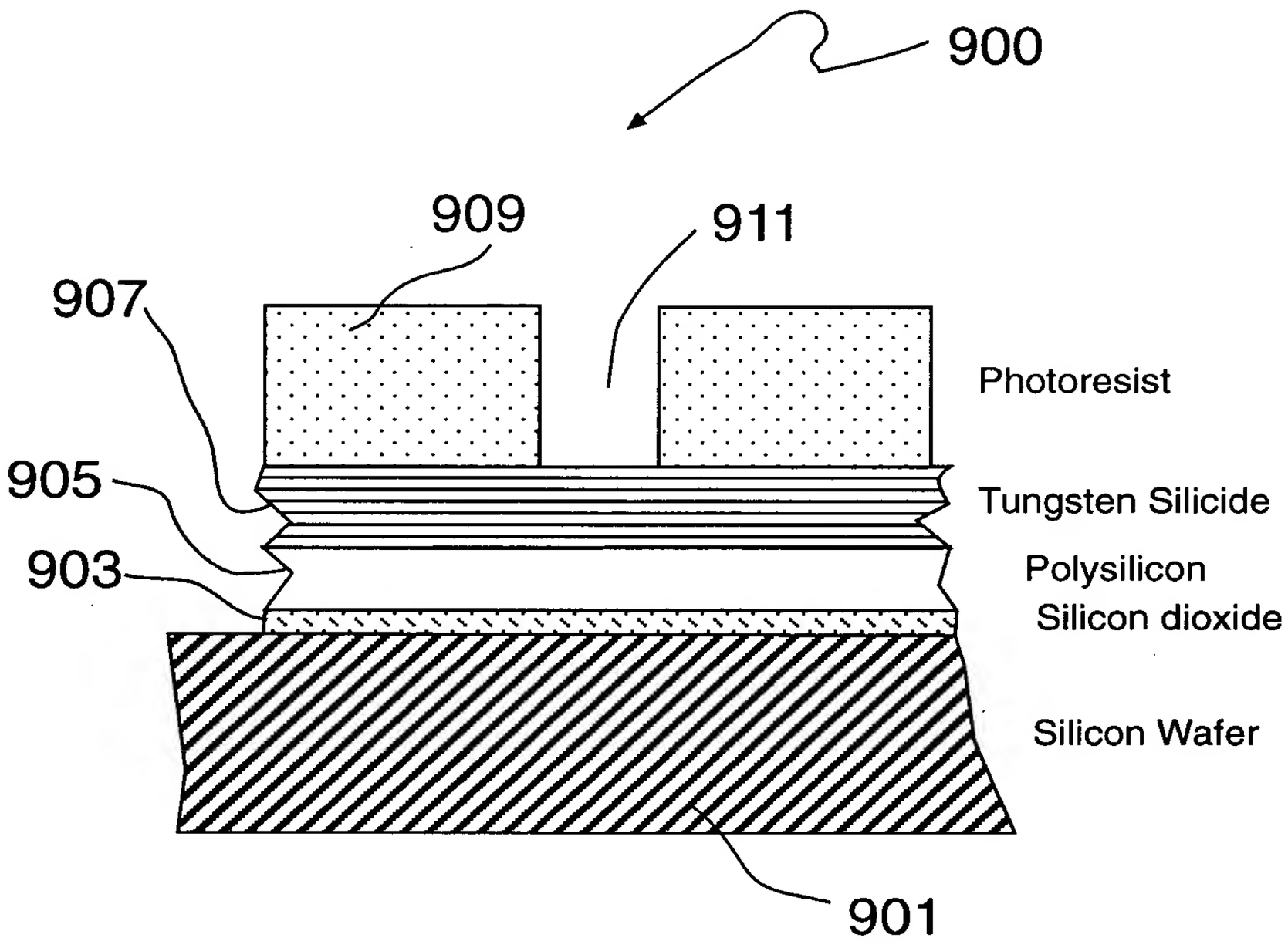
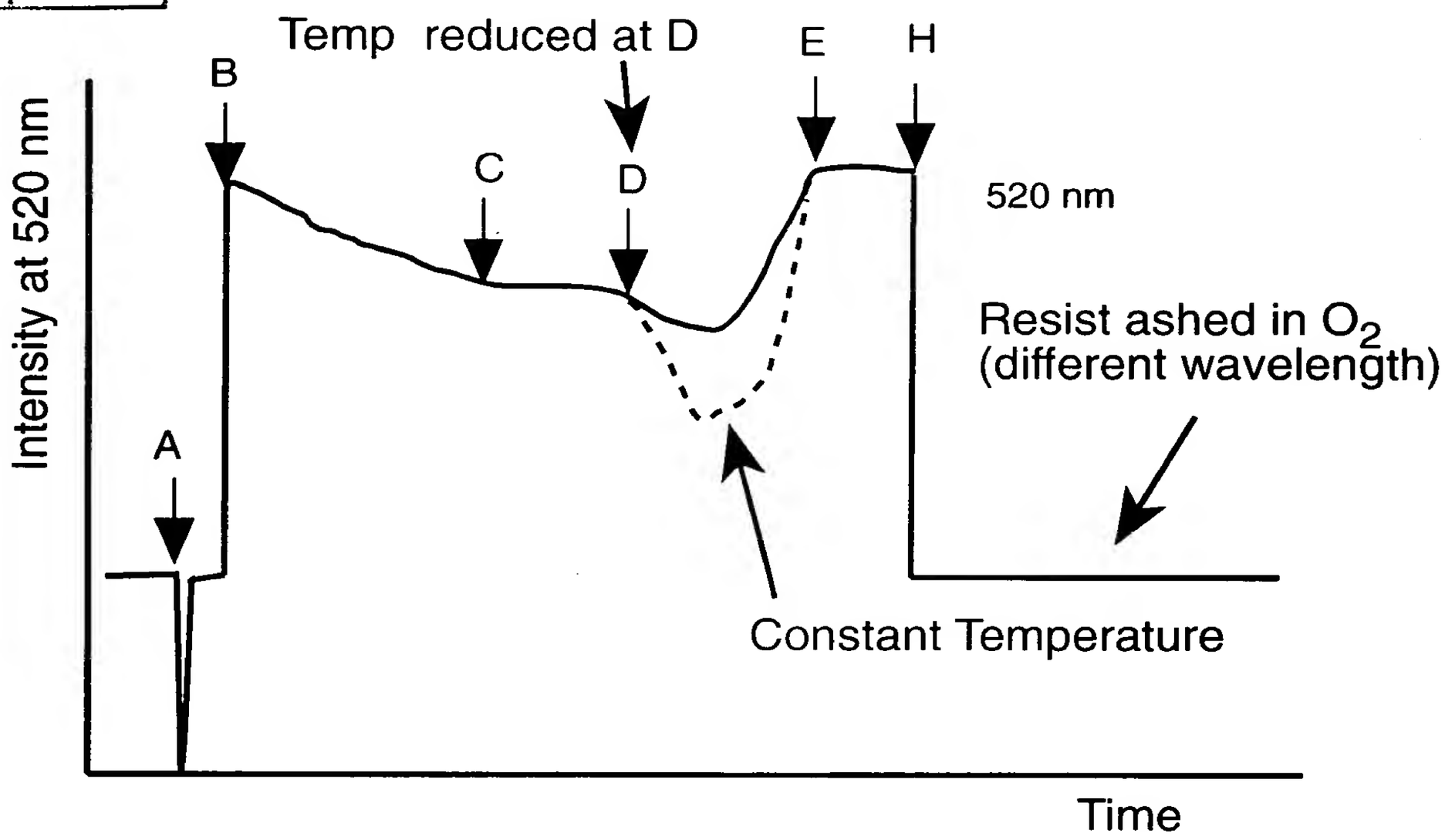
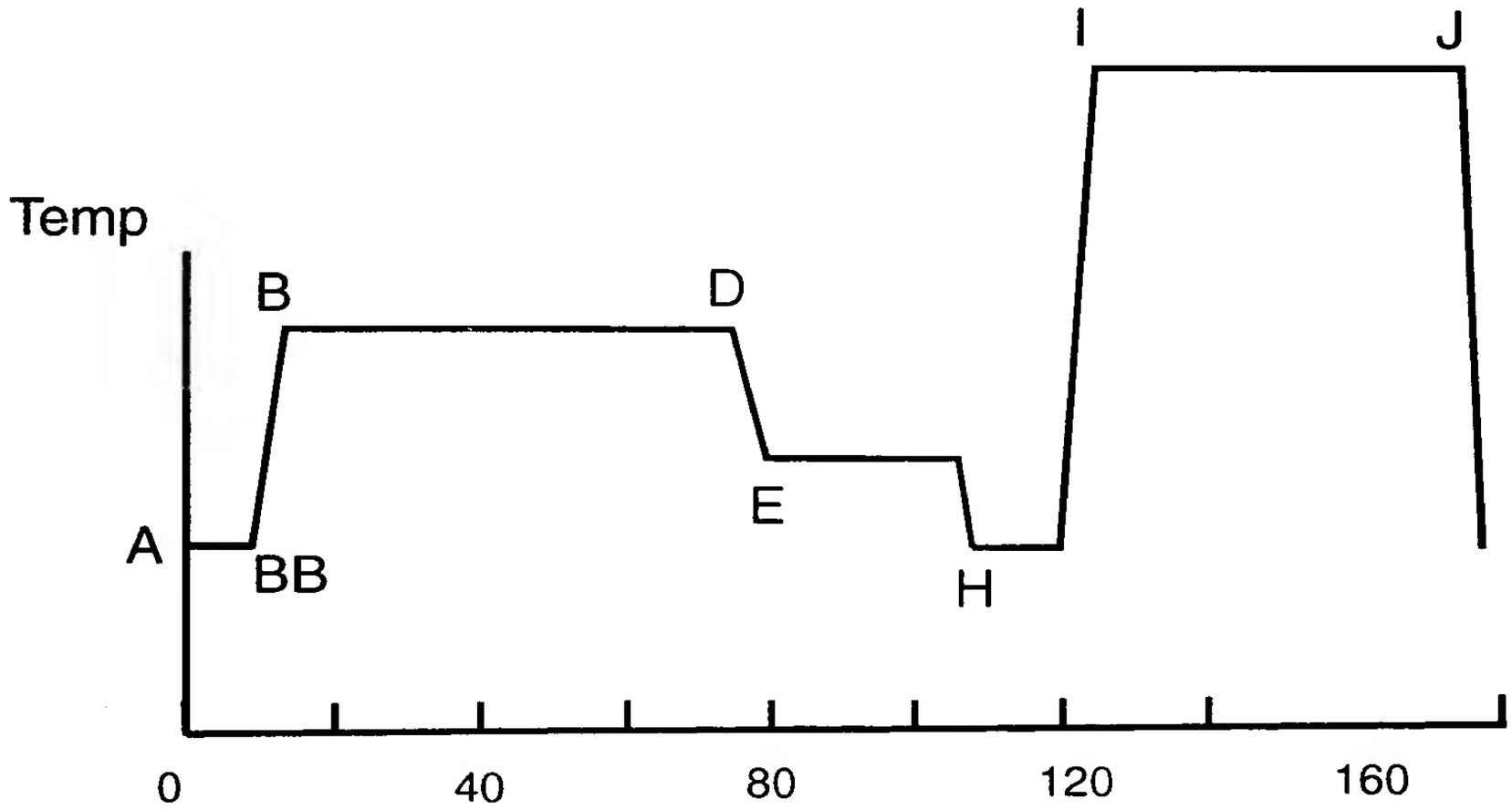


Fig. 9





A. SF_6 native oxide "breakthrough"
B. Cl_2 plasma is ignited
C. WSi_x begins to clear (endpoint)
D. Polysilicon is exposed
E. Polysilicon cleared to oxide
H. Plasma extinguished and O2 feed gas flow is started
I. O_2 plasma is started
J O_2 plasma is extinguished.

Fig. 10